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Our File No. NWN01-002-DIV-US

Jonathan M. Blanchard, Ph.D.

Name

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Signature

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:

Chad Mirkin, et al.

Serial No. 10/671,381

Filing Date: September 25, 2003

For SCANNING PROBE MICROSCOPY  
PROBE AND METHOD FOR  
SCANNING PROBE CONTACT  
PRINTING

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)  
)  
) Examiner To Be Assigned  
)  
) Group Art Unit No. 2881  
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**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. § 1.56, Applicants request that citation and examination of the references identified on the attached PTO-1449 form, be made during the course of examination of the above-referenced application for United States Letters Patent.

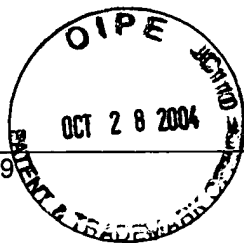
This application is a divisional application of Serial No. 10/440,022. Accordingly, all information previously submitted to and/or cited by the Examiner is not provided, according to 37 C.F.R. § 1.98(d).

Respectfully submitted,

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Form PTO-1449 (Rev. 8-88)	Attorney Docket No. NWN01-002-DIV-US	Serial No. 10/671,381
<b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)	Applicant: Chad Mirkin, et al.	
	Filing Date: September 25, 2003	Group: 2881

### U.S. PATENT DOCUMENTS

Examiner Initial*		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	A1	6,291,140	09/2001	Andreoli, et al.			
	A2	5,923,637	07/1999	Shimada, et al.			
	A3	5,610,898	03/1997	Takimoto, et al.			
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	A5	2003/0049381	03/2003	Mirkin, et al.			

### OTHER ITEMS - NON PATENT LITERATURE DOCUMENTS

Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages

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	A7	Kumar, A., et al., "Patterning Self Assembled Monolayers: Applications in Material Science", 1994, Langmuir, 10, pp. 1498-1511.
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	A9	Branch, D.W., et al., "Microstamp Patterns of Biomolecules for High-Resolution Neuronal Networks", 1998, Medical and Biological Engineering and Computing, vol. 36, pp. 135-141.
	A10	Marzolin, C., et al., "Patterning of a Polysiloxane Precursor to Silicate Glasses by Microcontact Printing", 1998, Thin Solid Films, 315, pp. 9-12.
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	A15	Khoo, M., et al., "Micro Magnetic Silicone Elastomer Membrane Actuator", 2001, Sensors and Actuators, 89(3), pp. 259-266.
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Examiner	Date Considered
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

A17	Hertel, T., et al., "Manipulation of Individual Carbon Nanotubes and Their Interaction with Surfaces", 1998, Journal of Physical Chemistry B, Vol. 102, pp. 910-915.
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